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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **Manabu NAKAMURA et al.**

Group Art Unit: **2891**

Application Number: **10/659,748**

Examiner: **Bradley Smith**

Filed: **September 11, 2003**

Confirmation Number: **3468**

For: **METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE
HAVING GATE OR TUNNEL INSULATION FILM**

Attorney Docket Number: **031140**

Customer Number: **38834**

AMENDMENT UNDER 37 C.F.R. § 1.116
EXPEDITED PROCESSING REQUESTED

Mail Stop: AF

Commissioner for Patents

P. O. Box 1450

Alexandria, VA 22313-1450

June 7, 2007

Sir:

In response to the Office Action dated March 7, 2007, Applicants amend the claims as follows and submit the following remarks.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 6 of this paper.